

Table - Deposition Techniques

Coating Process (1)*	Substrate	Resultant Coating
* Note: The numbers in brackets refer to the Notes following this table.		
A. Chemical Vapour Deposition (CVD)	<p>"Superalloys"</p> <p>Ceramics and Low-expansion glasses (14)</p> <p>Carbon-carbon, Ceramic and Metal "matrix" composites"</p> <p>Cemented tungsten carbide (16), Silicon carbide</p> <p>Molybdenum and Molybdenum alloys Beryllium and Beryllium alloys Sensor window materials (9)</p>	<p>Aluminides for internal passages Silicides Carbides Dielectric layers (15)</p> <p>Silicides Carbides Refractory metals Mixtures thereof (4) Dielectric layers (15) Aluminides Alloyed aluminides (2)</p> <p>Carbides Tungsten Mixtures thereof (4) Dielectric layers (15)</p> <p>Dielectric layers (15) Dielectric layers (15) Dielectric layers (15)</p>
B. Thermal-Evaporation Physical Vapour Deposition (TE-PVD) B. 1. Physical Vapour Deposition (PVD): Electron-Beam (EB-PVD)	<p>"Superalloys"</p> <p>Ceramics and Low-expansion glasses (14)</p> <p>Corrosion resistant steel (7)</p> <p>Carbon-carbon, Ceramic and Metal "matrix" composites"</p> <p>Cemented tungsten carbide (16), Silicon carbide</p> <p>Molybdenum and Molybdenum alloys Beryllium and Beryllium alloys Sensor window materials (9) Titanium alloys (13)</p>	<p>Alloyed silicides Alloyed aluminides (2) MCrAlX (5) Modified zirconia (12) Silicides Aluminides Mixtures thereof (4)</p> <p>Dielectric layers (15)</p> <p>MCrAlX (5) Modified zirconia (12) Mixtures thereof (4)</p> <p>Silicides Carbides Refractory metals Mixtures thereof (4) Dielectric layers (15)</p> <p>Carbides Tungsten Mixtures thereof (4) Dielectric layers (15)</p> <p>Dielectric layers (15) Dielectric layers (15) Borides Dielectric layers (15) Borides Nitrides</p>